

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appln. No: To Be Assigned
Applicant: Norisato Shimizu et al.
Filed: July 28, 2003
Title: SWITCH AND METHOD FOR MANUFACTURING THE SAME
TC/A.U.:
Examiner:
Docket No.: MAT-8448US

INFORMATION DISCLOSURE STATEMENT

Mail Stop Patent Application
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. §§ 1.97 and 1.98 and to the duty of disclosure set forth in 37 C.F.R. § 1.56, the Examiner in charge of the above-identified application is requested to consider and make of record the references listed on the PTO 1449 (R&P) submitted herewith. A copy of each of the listed references is also enclosed.

Although the information submitted herewith may be "material" to the Examiner's consideration of the subject application, this submission is not intended to constitute an admission that such information is "prior art" as to the claimed invention.

In accordance with 37 C.F.R. § 1.97(g), the filing of this Information Disclosure Statement shall not be construed to mean that a search has been made.

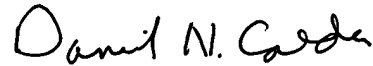
The enclosed publications are referenced in the specification as follows:

- 1) "Wafer-level packaged RF-MEMS switches fabricated in a CMOS fab" by H.A.C.Tilmans et al. IEEE 2001 IEDM Tech. Digest 01 921-924 on page 1, line 11;
- 2) "A Low Voltage Actuated Microelectromechanical Switch for RF Application" by Dooyoung Hah et al. JPN.J. Appl. Phys. Vol. 40 (2001) pp. 2721-2724 on page 2, line 13;
- 3) "A Rotational Comb-Driven Micromirror with a Large Deflection Angle and Low Drive Voltage" by Osamu Tuboi et al. IEEE 2002 MEMS Tech. Digest, pp. 532-535 on page 2, line 14 and page 18, lines 7/8.

This Information Disclosure Statement is being filed concurrently with the above-referenced application.

Respectfully submitted,

RatnerPrestia



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Daniel N. Calder, Reg. No. 27,424
Attorneys for Applicants

DNC/kc

Enclosures: PTO Form 1449
(3) Publications

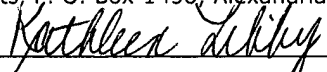
Dated: July 28, 2003

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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

SHEET 1 of 1

Complete if Known

Application Number To Be Assigned

Filing Date July 28, 2003

First Named Inventor Norisato Shimizu

Art Unit

Examiner Name

Attorney Docket No. MAT-8448US

NON-PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
		H.A.C. TILMANS et al., "Wafer-level packaged RF-MEMS switches fabricated in a CMOS fab" IEEE 2001 IEDM Tech. Digest 01 921-924 (41.4.1-41.4.4)	<input type="checkbox"/>
		DOOYOUNG HAH et al., "A Low Voltage Actuated Microelectromechanical Switch for RF Application" JPN.J. Appl. Phys. Vol. 40(2001) pp. 2721-2724	<input type="checkbox"/>
		OSAMU TUBOI et al., "A Rotational Comb-Driven Micromirror with a Large Deflection Angle and Low Drive Voltage" IEEE 1002 MEMS Tech. Digest, pp. 532-535	<input type="checkbox"/>
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

¹Applicant's unique citation designation number (optional).²Applicant is to place a check mark here if English language translation is attached.

The collection of information is required by 37 CFR 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 120 minutes to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, Washington, DC 20231. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. **SEND TO:**
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